



Developments in Sub-Aperture Techniques for Precision Mirror Fabrication

presented to:

Technology Days in the Government
Mirror Development
August 25-27 2008

Aric Shorey, Paul Dumas and
Paul Murphy
QED Technologies®

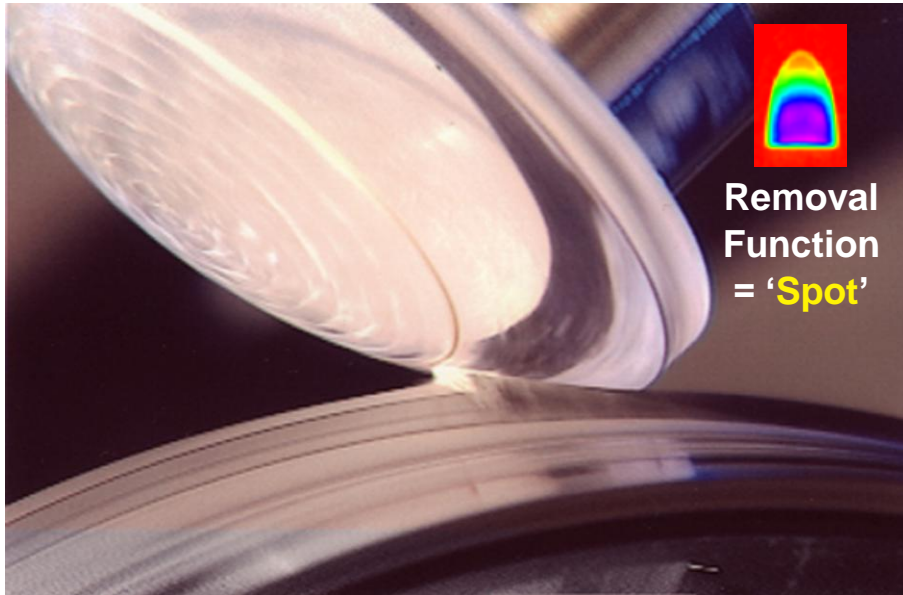
1040 University Avenue • Rochester, NY • USA
Tel: +1 (585) 256-6540 • Fax: +1 (585) 256-3211
mooney@qedmrf.com • www.qedmrf.com

Acknowledgements:

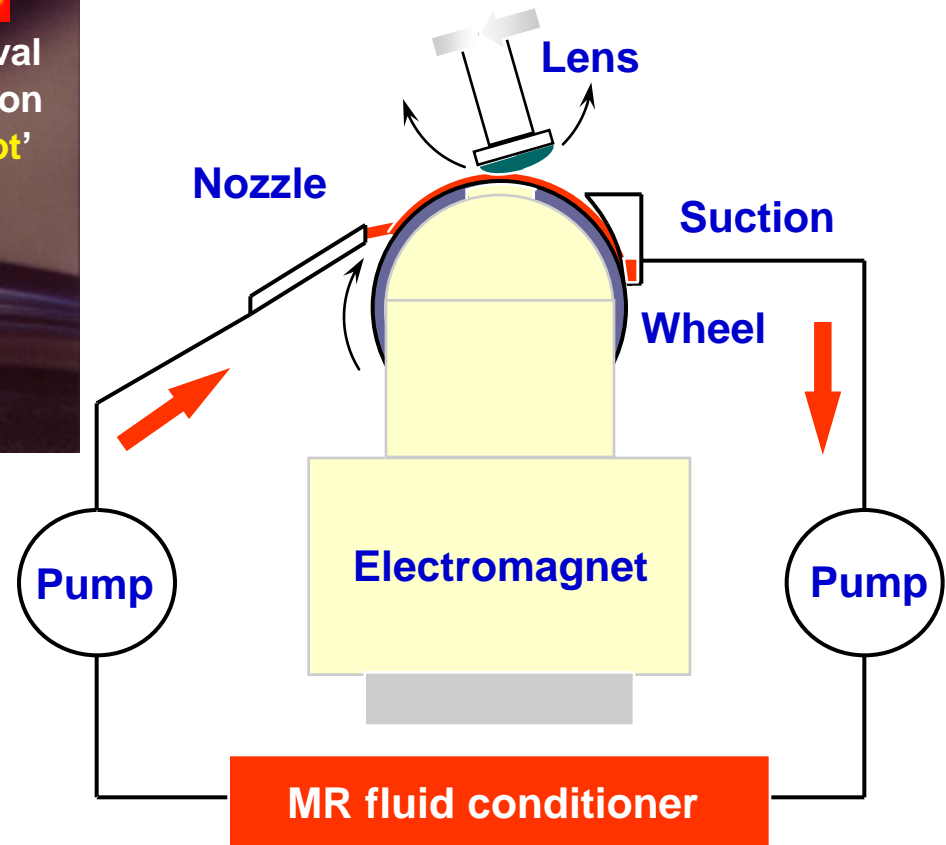
John West, John Hraba
Dr. Philip Stahl - NASA
MSFC
Scott Antonille – NASA
GSFC

- **Brief MRF[®] technology introduction**
- **Demonstration of performance of 2-meter MRF platform**
- **Increase in aspheric departure that can be measured with Sub-Aperture Stitching Interferometry (SSI_A[®])**

Magnetorheological Finishing (MRF) – How it works



MRF conforms to the workpiece surface



MRF – Breakthrough Technology

The MRF polishing tool:

- never dulls or changes
- is interferometrically characterized
- is easily adjusted
- conforms to part shape - works on complex shapes (flat, sphere, asphere, cylinder, freeform...)
- has high removal rates
- removal based on shear stress so applies very low normal load on abrasive, improving surface integrity
- determinism leads to high convergence rate

These attributes lead to a production-oriented, deterministic, computer-controlled polishing and figuring technique.

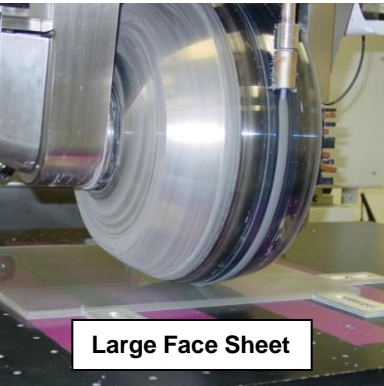
Production proven: more than 100 machines worldwide

Polishing optics from 1mm to >1 meter

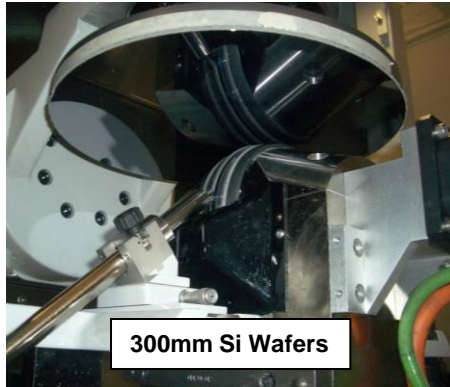


- **Q22-XE** – <100 mm in diameter.
- **Q22-X** - Up to 200 mm in diameter.
- **Q22-Y** - Raster tool path, up to 200 mm in size.
- **Q22-400X** - Up to 400 mm in diameter.
- **Q22-750P2** - Plano optics up to 750 mm x 1,000 mm in size.
- **Q22-950F-Polishing Center**– Freeform optics up to 950 x 1,250mm with pre-polishing capabilities
- **Q22-2000F**– Freeform optics up to 2+ meters
- **SSI®** -- Subaperture Stitching Interferometer (SSI) for high precision metrology.
- **SSI-A®** -- Subaperture Stitching Interferometer (SSI) for high precision asphere metrology.

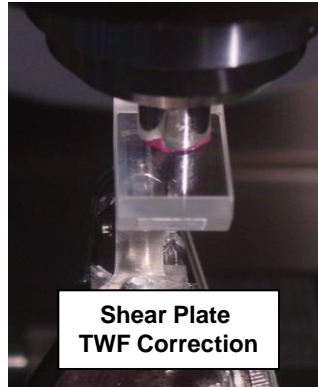
Range of MRF Applications



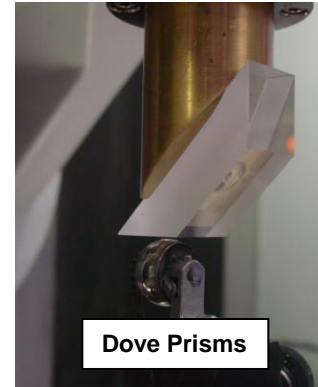
Large Face Sheet



300mm Si Wafers



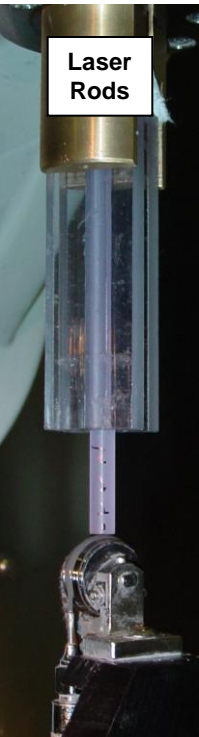
Shear Plate
TWF Correction



Dove Prisms



Steep Concave



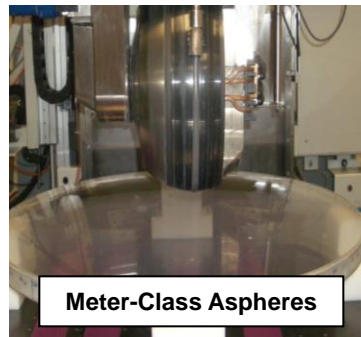
Laser
Rods



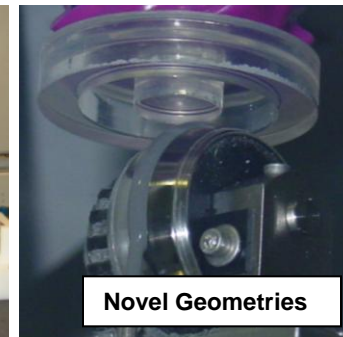
Lightweight
Primary Mirror



Lightweight
SiC Mirror



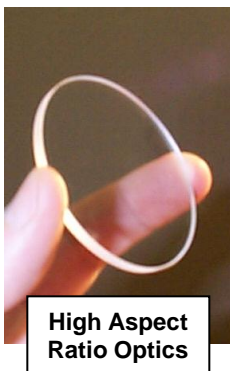
Meter-Class Aspheres



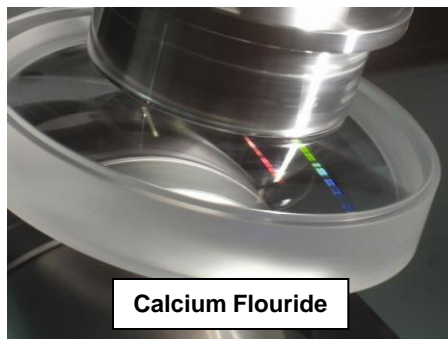
Novel Geometries



Steep Aspheres



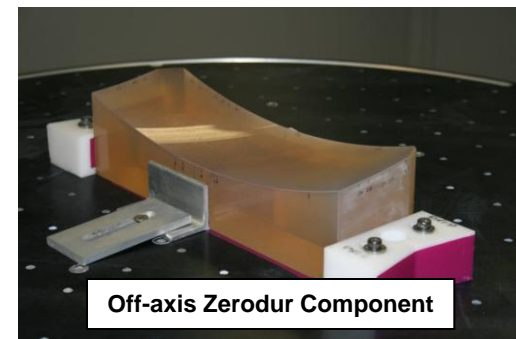
High Aspect
Ratio Optics



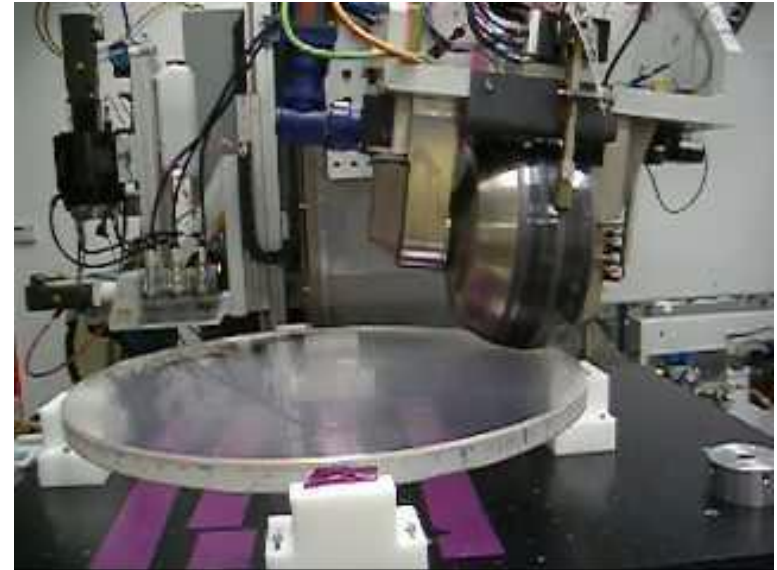
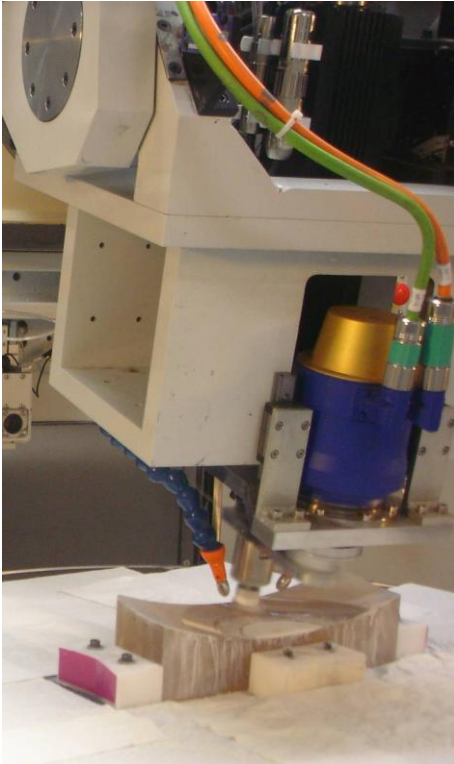
Calcium Fluoride



Sapphire Windows



Off-axis Zerodur Component



- **Q22-950F can be outfitted with pad polishing and MRF**
- **This allows the user to go from ground state to finished surface**

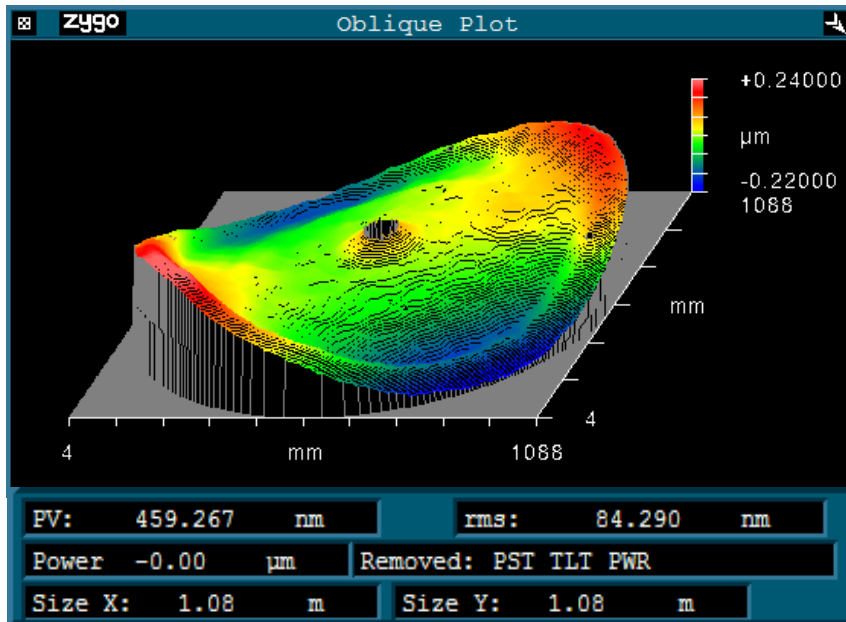


- 2-Meter Platform

- QED has successfully delivered and installed an MRF machine capable of polishing 2-meter diameter optics
 - This machine is installed and has passed all acceptance test requirements
- **Mirror Details**
 - Outer Diameter: ~1.1 m (~43")
 - Inner Diameter: ~0.1 m (~4")
 - Radius of Curvature: ~3 m (~120")
 - Material: Low expansion material
- **Metrology**
 - Full aperture
 - Standard surface reflection test

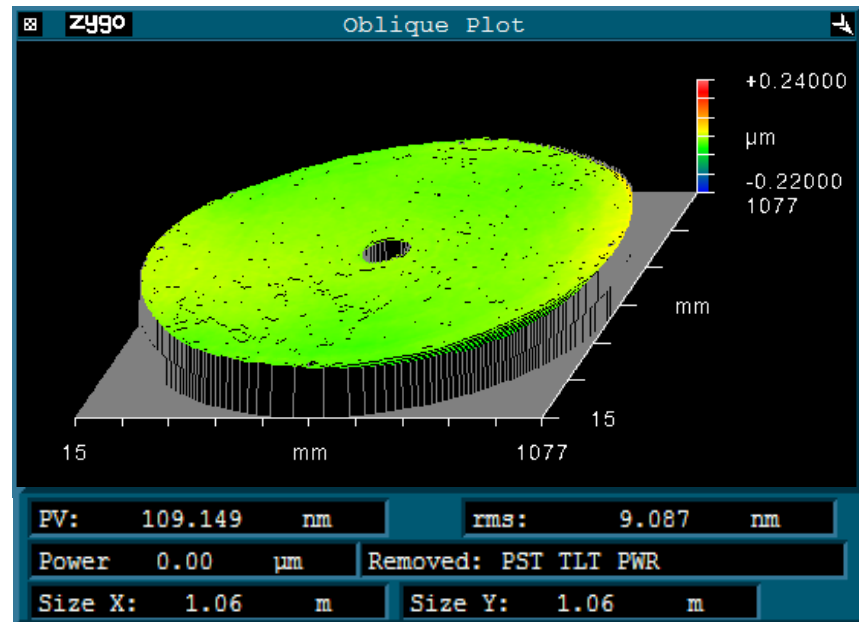
Figure Correction – Large Primary *Global Figure over CA*

Initial



RMS = 84 nm ($\sim \lambda/7$)

Final

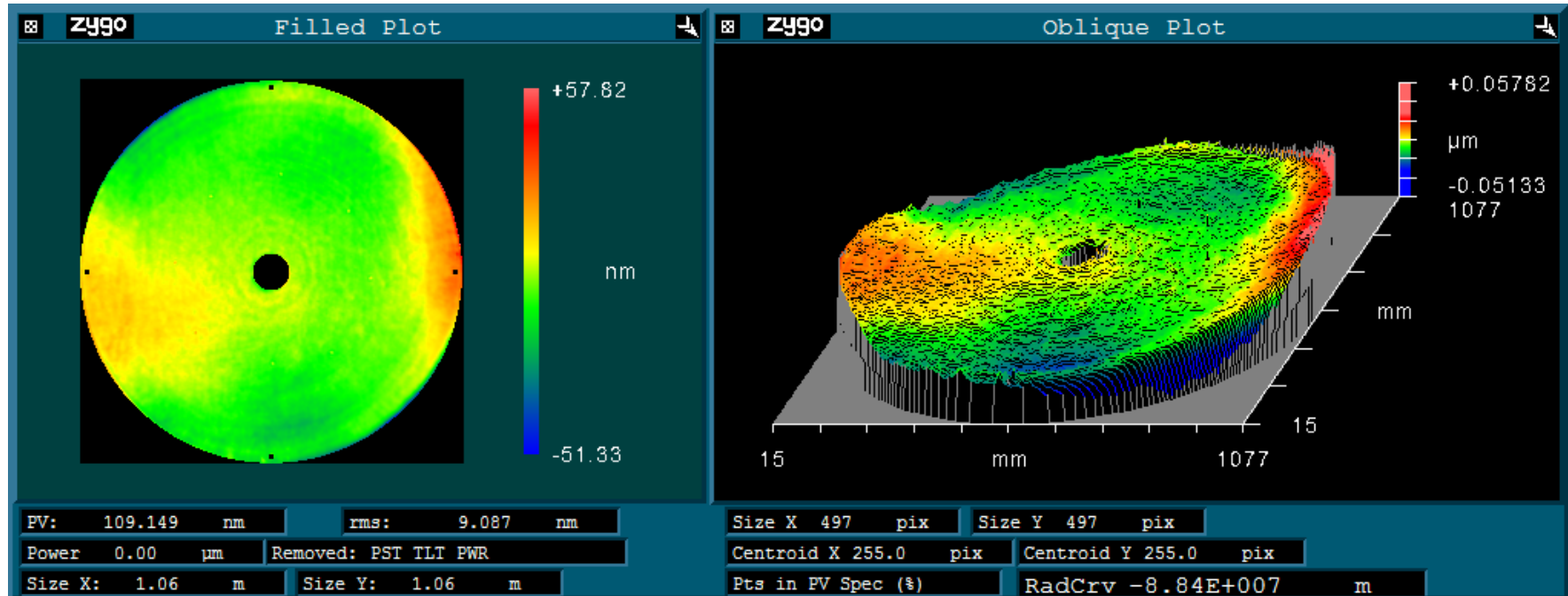


RMS = 9 nm ($\sim \lambda/70$)

- Only **20 hours** of polishing time
- Only **2 iterations** of MRF

Fast Convergence on
Meter-Class Optics!

Figure Correction – Large Primary *Close Look at Final Quality*

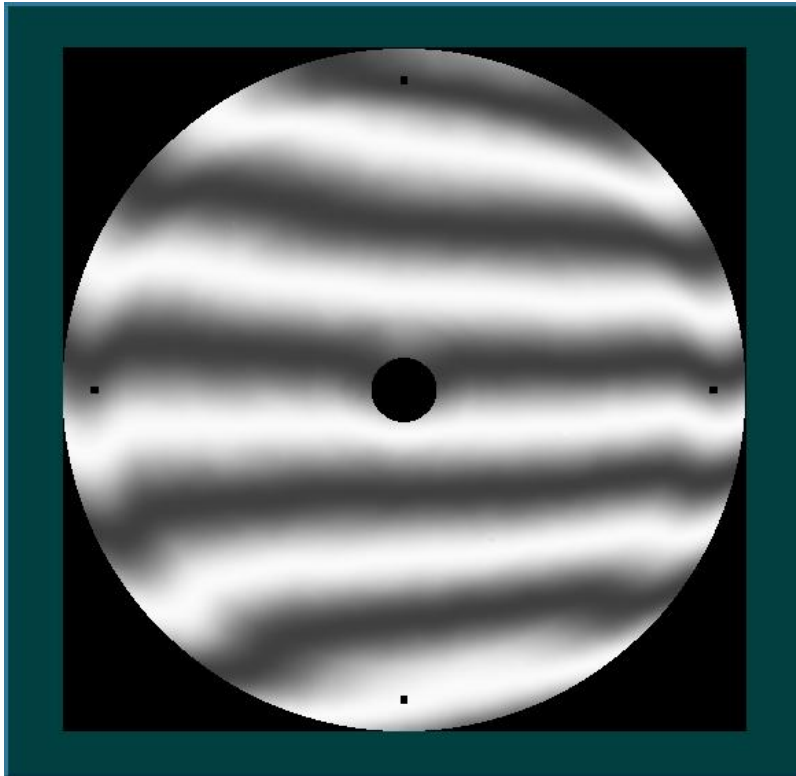


RMS = 9 nm ($\sim \lambda/70$)

- Metrology repeatability was limiting factor (due to time constraints)
- Much of residual astigmatism due to mounting distortions
- Could correct even further with improved metrology

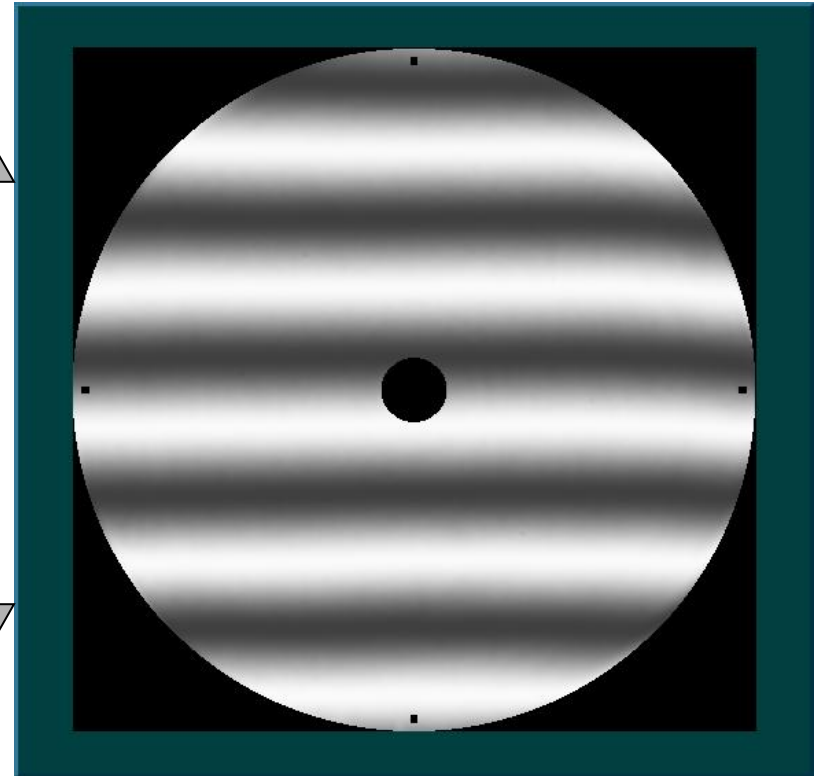
Figure Correction – Large Primary *Synthetic Fringes Before & After*

Initial



1.1 m (43") Diameter

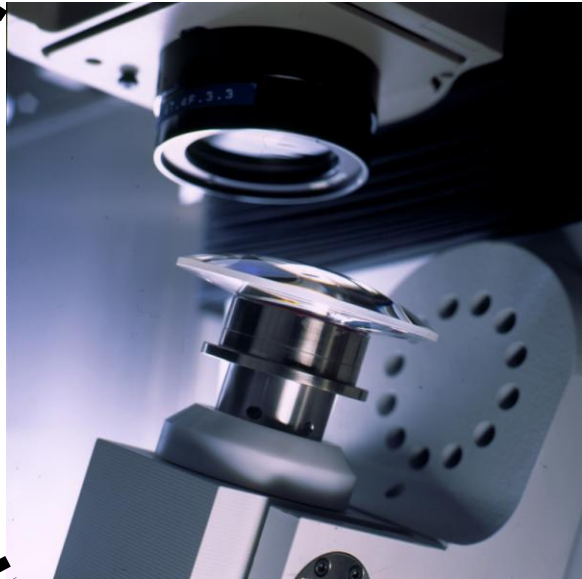
Final



- **2 MRF Iterations: 14 hrs + 6 hrs = 20 hours total**
- **Overnight, unattended operation**
- **Fast, deterministic convergence on meter-class mirrors!**

Subaperture Stitching Interferometer (SSI®)

- Precision six axis machine
- Standard Zygo® 4" or 6" interferometer
- QED control software: automation + advanced algorithms

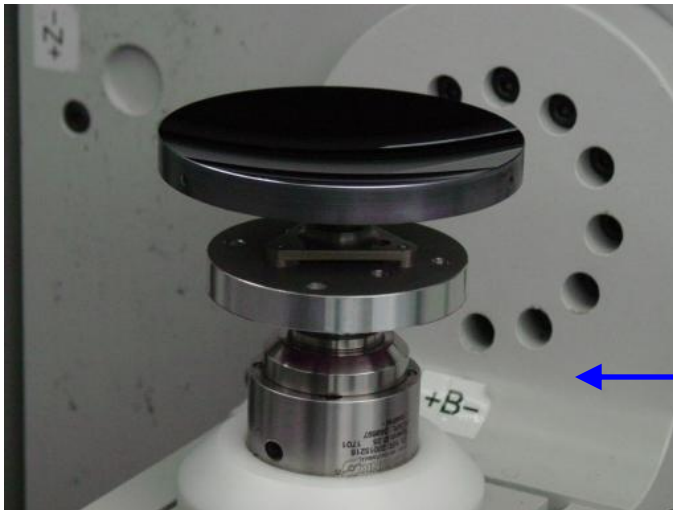
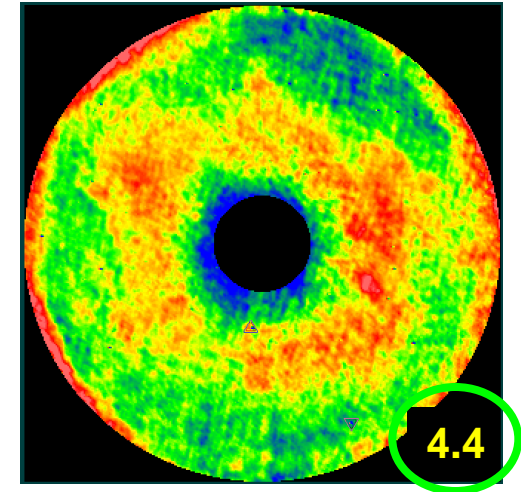


SSI advantages

- Cost-effective measurement of larger apertures
- Automatic, inline calibration of systematic error
- Increased lateral resolution
- *Measures mild aspheres without dedicated nulls!*

- R –226 mm; CA 100 mm; $\sim 25 \lambda$ from b.f.s.
- Secondary mirror for the PICTURE / SHARPI programs
- Good agreement with vendor's null test
 - But again, note the finer structure resolved

Stitch map

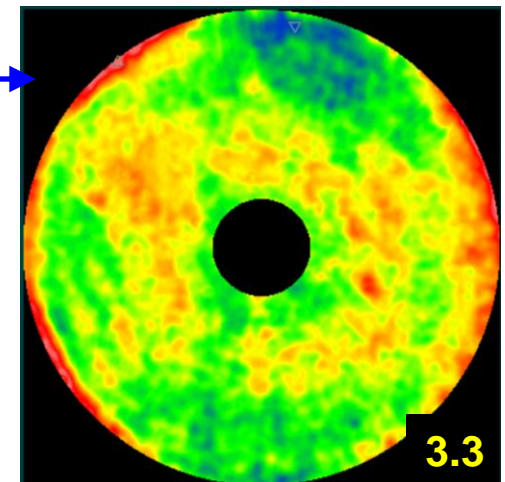


Null test data courtesy
of Jay Schwartz, L3-
SSG-Tinsley

Scale +/- 12.5 nm

Test part courtesy of
Scott Antonille, NASA
Goddard

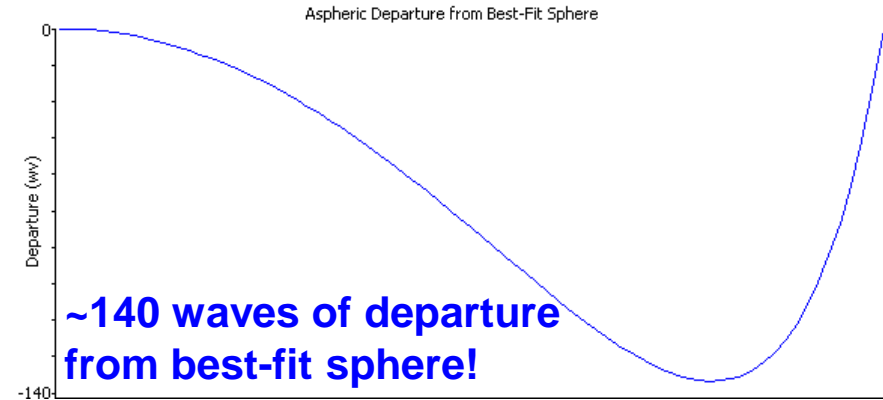
Conic null test



New SSI-A software release!

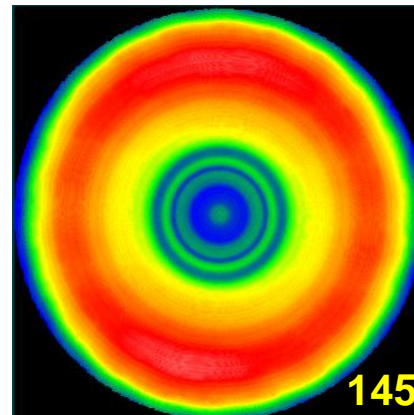
- More aspheric capability
 - Up to ~200 waves from best-fit sphere *without dedicated null lenses*
 - Aperture converter and small Transmission Spheres enable more radii and R/#s

- Enhanced usability
 - Consolidated advanced options reduces confusion
 - SSI setup wizards simplify configuring the SSI
 - and other conveniences!

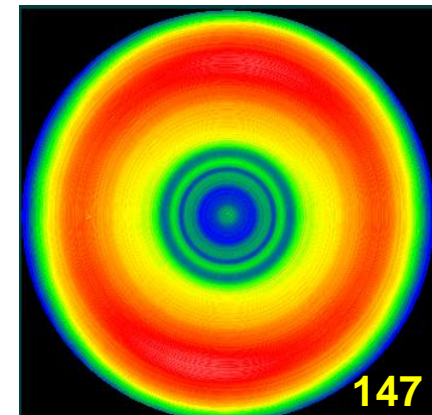


Excellent measurement reproducibility

Measurement with f/2.2

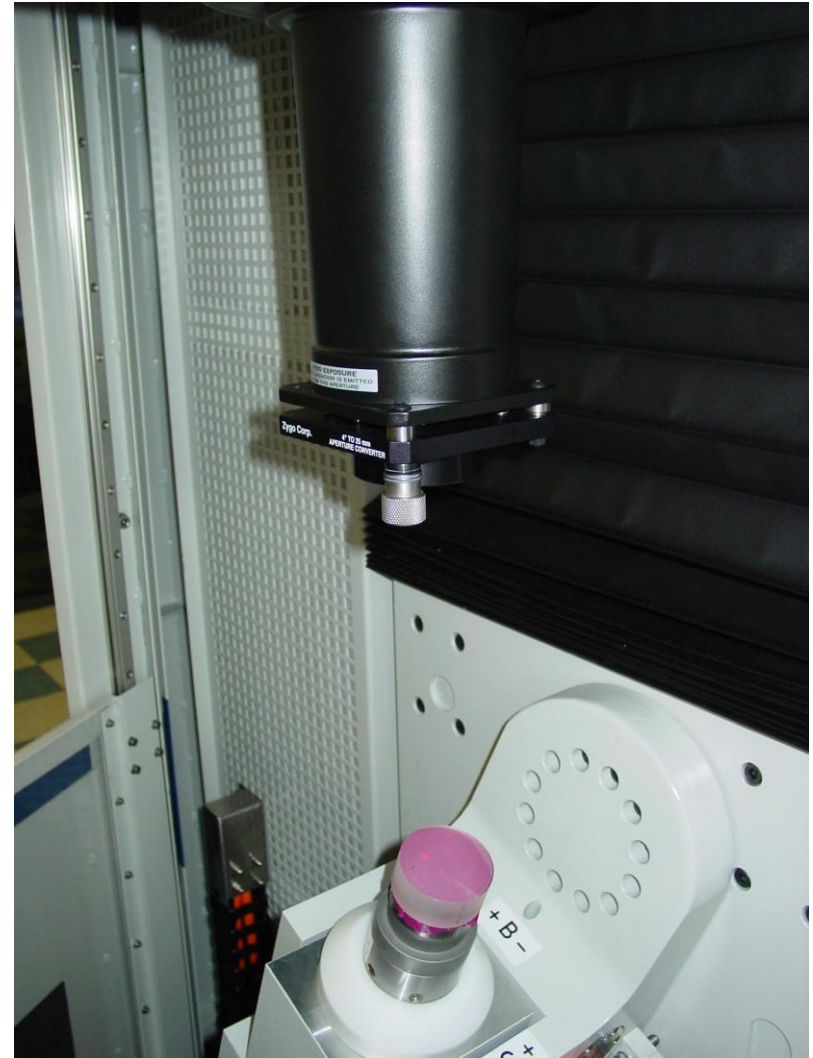


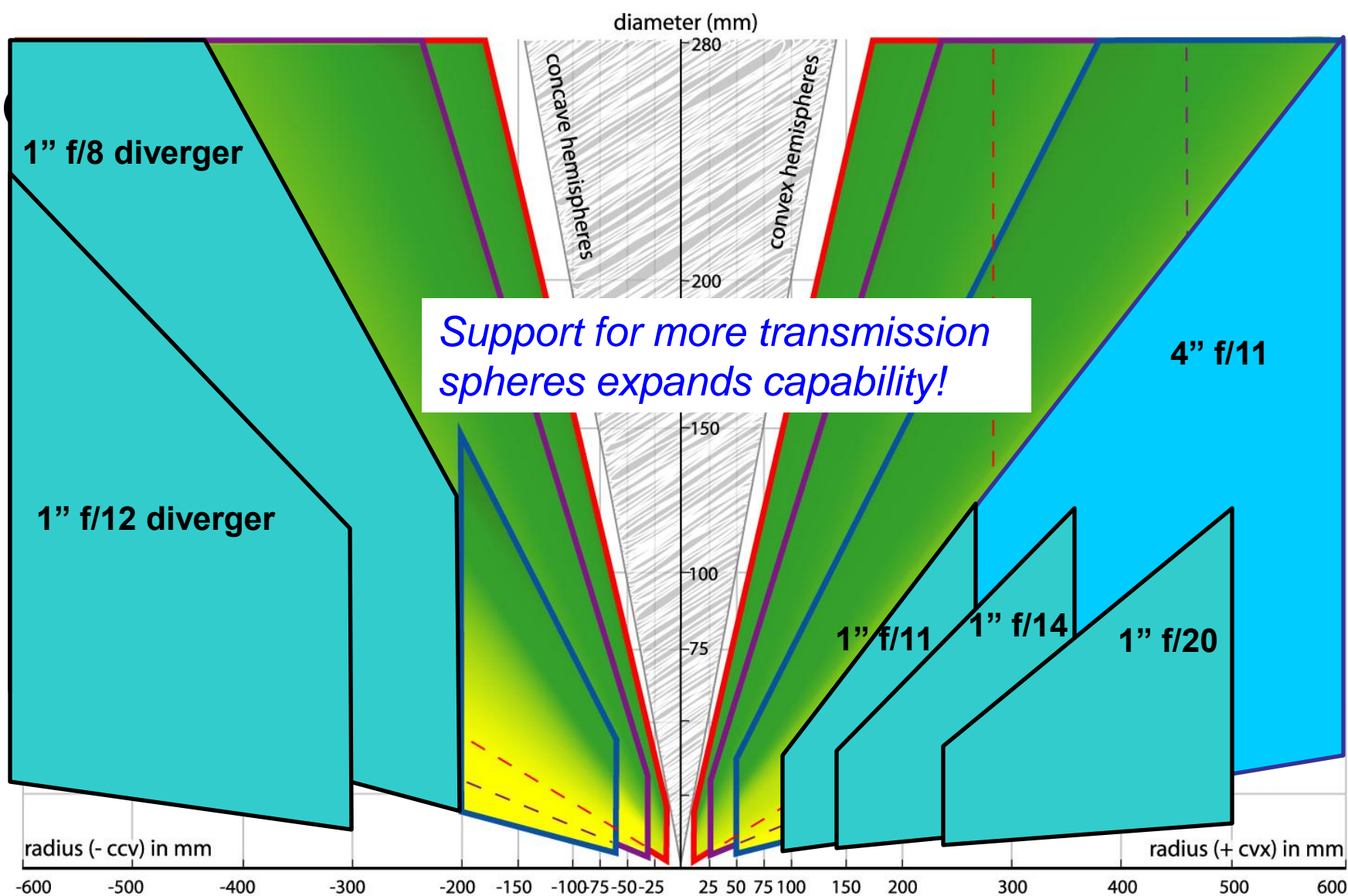
Measurement with f/3.3



Aperture converter and small transmission spheres

- Software enables use of aperture converters and small TSs
 - Higher magnification; more aspheric departure possible
 - Enables more parts to fit within the SSI 1 meter-long envelope

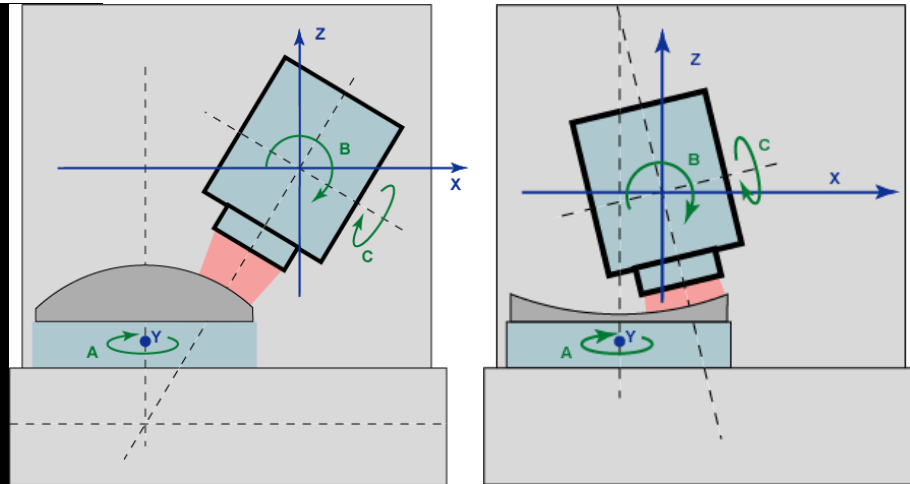
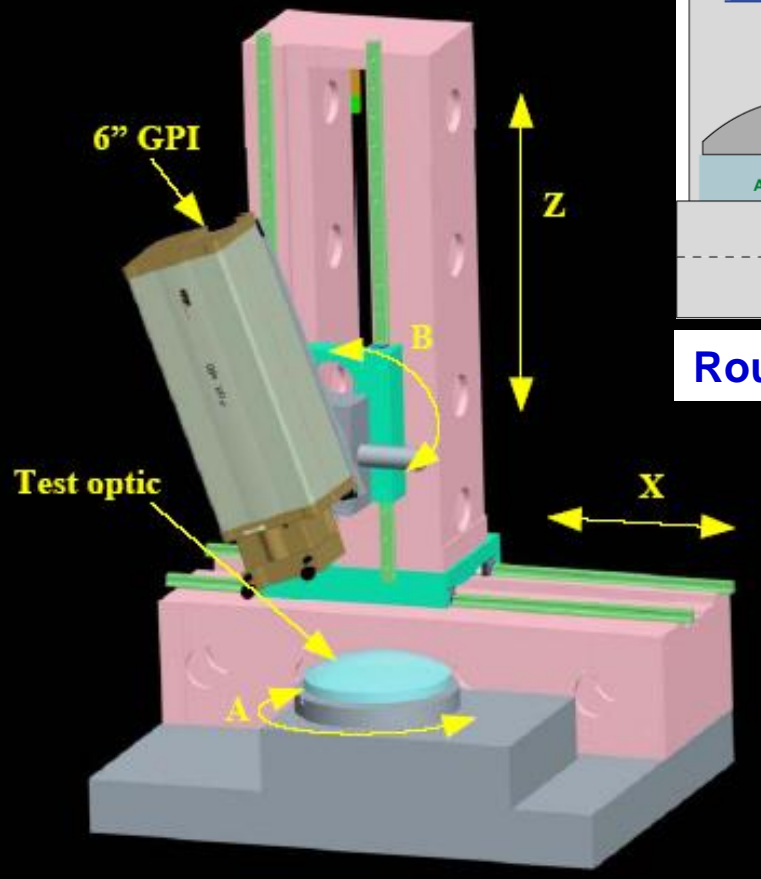




Support for more transmission spheres expands capability!

- Benefits specific to large optics
 - Avoid fabrication of huge transmission spheres and null optics for convex surfaces (e.g. secondary mirrors)
 - No dedicated nulls (and painful calibration of them) for mild to moderate aspheric departures
 - Reduced cavity lengths (and air turbulence) for concave optics (via use of diverging TSs)
 - Improved spatial resolution (for edges and MSFs)
- Scaling up involves significant hardware changes
 - Increased size, larger X travel; tilt the interferometer, not the part
 - Need to avoid the greater mechanical distortions for large parts
 - Interferometer size selection has some trade-offs
 - 6" mainframe: lower cost (especially for TSs), easier to move
 - Cycle times and possible accuracy trade-offs
 - (e.g. for a 1.5 m segment, 6": ~400 subapertures; 12": ~100)

sample concept:
“moving column”



Rough schematics of tilting interferometer

Stitching technology is scalable to larger optics in both vertical and horizontal configurations.

- Unique attributes of MRF give it the flexibility for polishing complex shapes to high precision with excellent convergence rates
- QED continues to extend the aperture size that can be finished and recently installed and demonstrated performance of a 2-meter freeform platform
 - Precision finishing of a mirror > 1 meter in size was demonstrated – 2 iteration, 20 hours of polishing
 - Very fast convergence and short cycle times demonstrated on meter-class optics
- Increased aspheric departure can now be measured using stitching interferometry (SSI_A) - ~200 waves of departure
- Stitching interferometry can be scaled to address meter class optics
- QED remains committed to delivering state-of-the-art solutions for optics fabrication challenges



Developments in Sub-Aperture Techniques for Precision Mirror Fabrication

presented to:

Technology Days in the Government
Mirror Development
August 25-27 2008

Aric Shorey, Paul Dumas and
Paul Murphy
QED Technologies®

1040 University Avenue • Rochester, NY • USA
Tel: +1 (585) 256-6540 • Fax: +1 (585) 256-3211
mooney@qedmrf.com • www.qedmrf.com

Acknowledgements:

John West, John Hraba
Dr. Philip Stahl - NASA
MSFC
Scott Antonille – NASA
GSFC